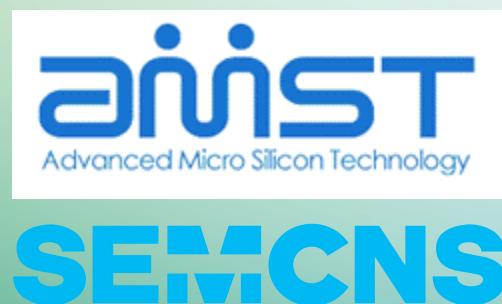




Optimization of thermo-mechanical characteristics of a probe card



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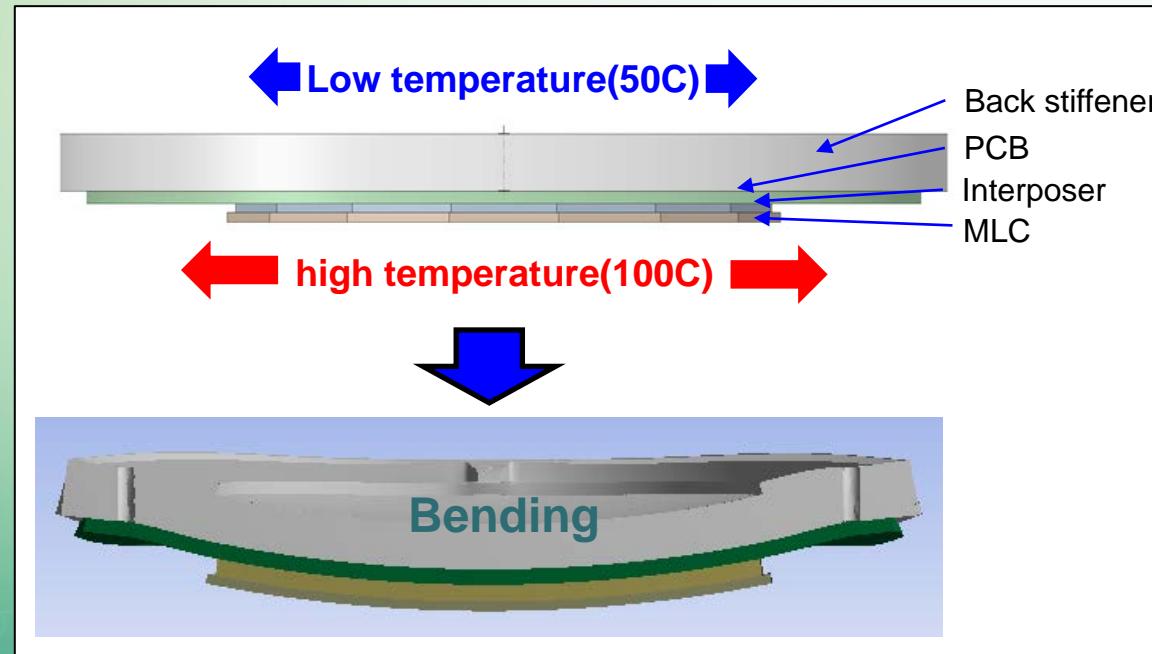
AGENDA

- INTRODUCTION
- SOLUTION
- OPTIMIZATION OF THERMAL PLANARITY
- OPTIMIZATION OF THERMAL ALIGNMENT
- SUMMARY

Introduction – 1

- Thermal planarity

- Thermal bending : CTE and thermal expansion by temperature gradient
- Main factor of thermal bending : Back-stiffener

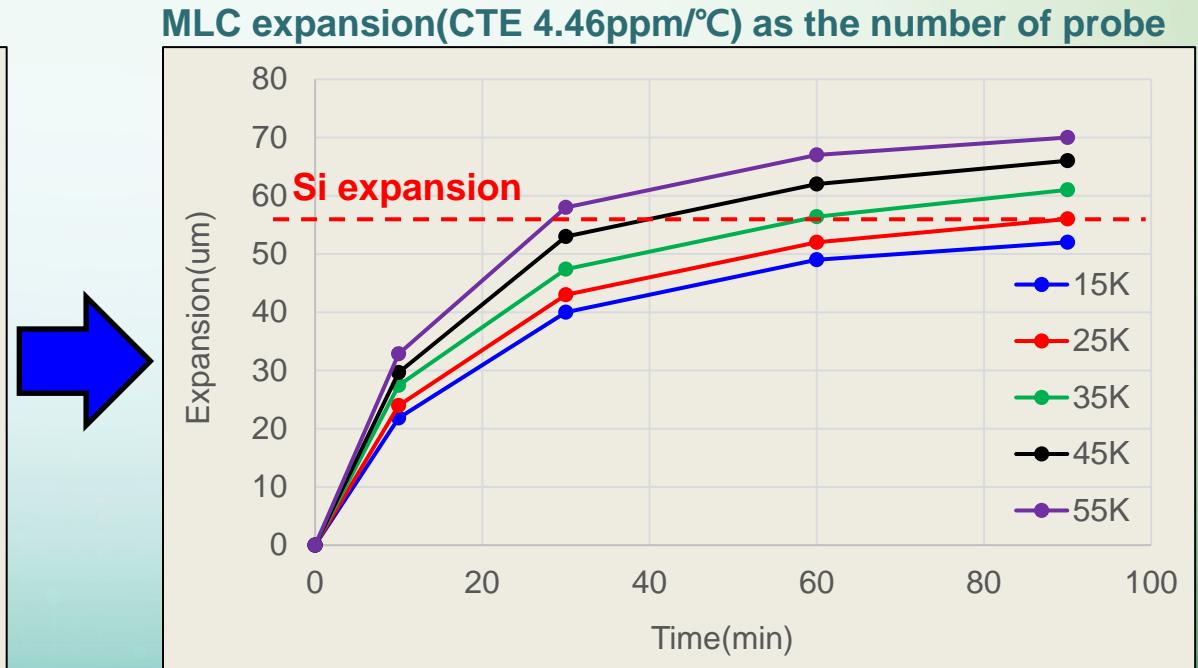
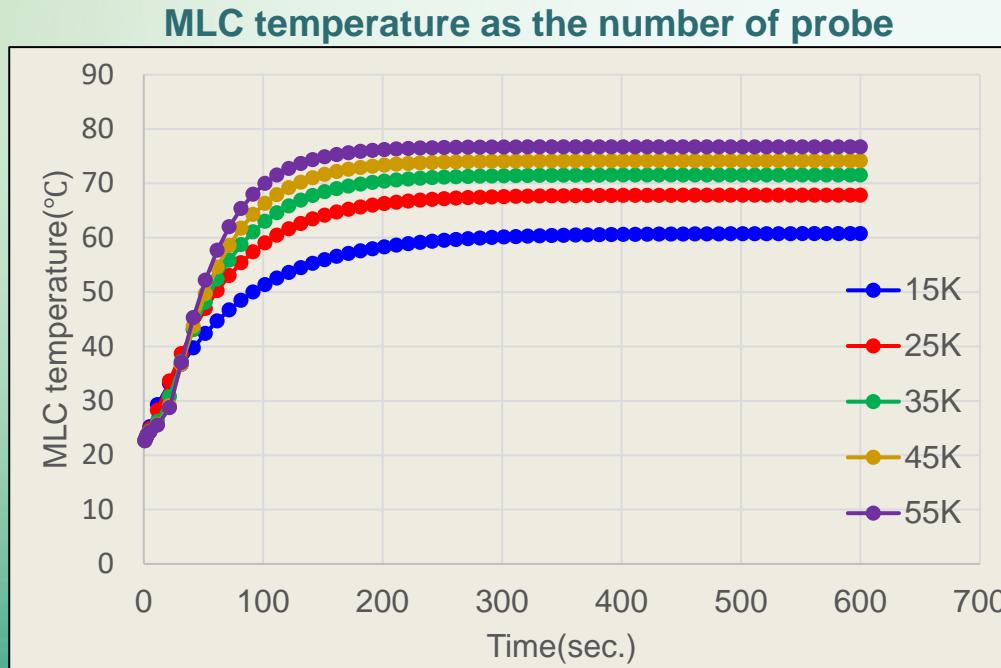


Configuration of Probe Card

| Part | Elastic modulus (GPa) | Thickness (mm) | material | CTE (ppm/ $^{\circ}$ C) | bending contribution |
|----------------|-----------------------|----------------|-------------|-------------------------|----------------------|
| Back stiffener | 200 | 20~30 | Based Steel | 10~20 | 80% over |
| PCB | 20~30 | 6~7 | FR4 | 20~30 | 4% |
| MLC | 130 | 5.5 | Ceramic | 4~5 | 15% |

Introduction - 2

- Thermal alignment
 - Thermal align miss-match : Difference of expansion between wafer and MLC
 - Number of probes : Important factor in selecting CTE of MLC



Solution

- **Optimization of thermal planarity**
 - Optimization of back-stiffener using FEA simulation
 - 1) Selection of material and CTE
 - 2) Shape and thickness
 - 3) Back-stiffener size
- **Optimization of thermal alignment**
 - Lower CTE MLC
 - 1) Improvement of thermal alignment applied low CTE MLC
 - 2) Stable probe counts applied low CTE MLC

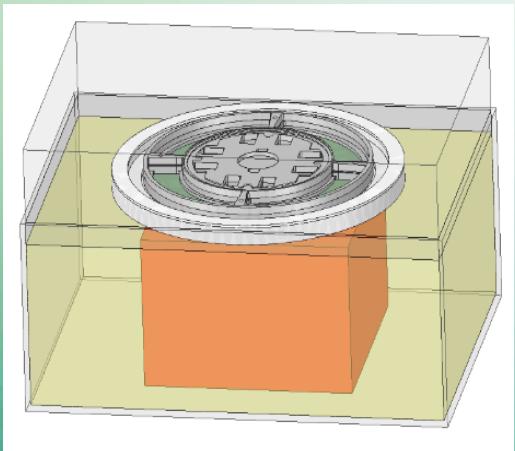
FEA system

- Probe card simulation using FEA

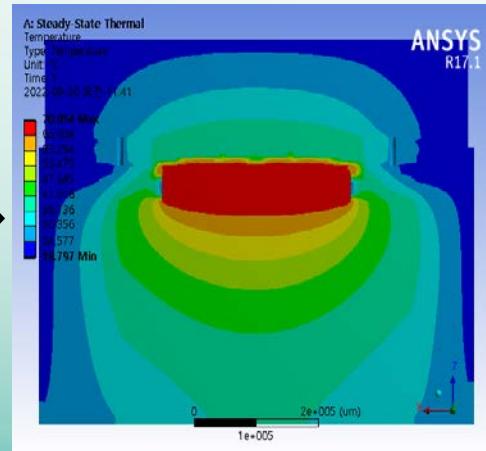
- FEA procedure

- 1) 3D full modeling
- 2) Transient thermal analysis
- 3) Import main part temperature
- 4) Static structural analysis

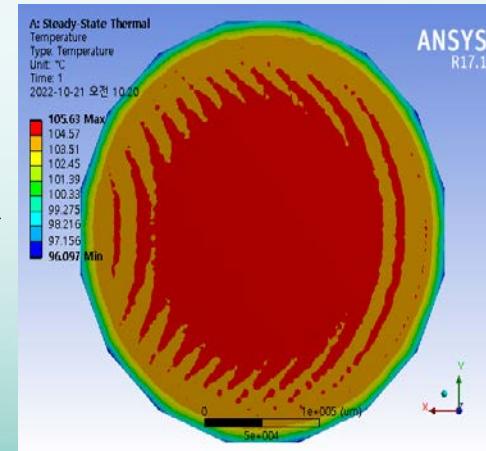
3D full modeling



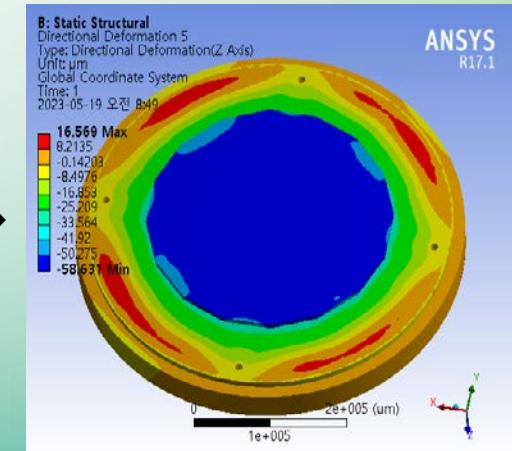
Transient thermal



Import main part



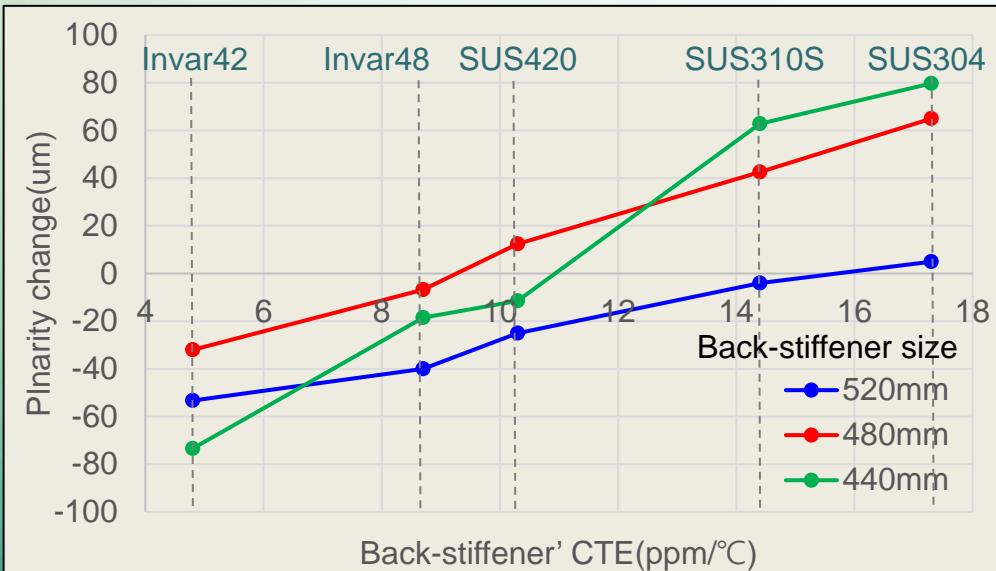
Static structural



Optimization of thermal planarity

- **Effect of back-stiffener's CTE(material)**
 - Increasing size of back-stiffener : Suitable for material with higher CTE
- **Effect of back-stiffener's thickness**
 - Amount of planarity change : Stable of back-stiffener with increasing size

Planarity change as back-stiffener's CTE

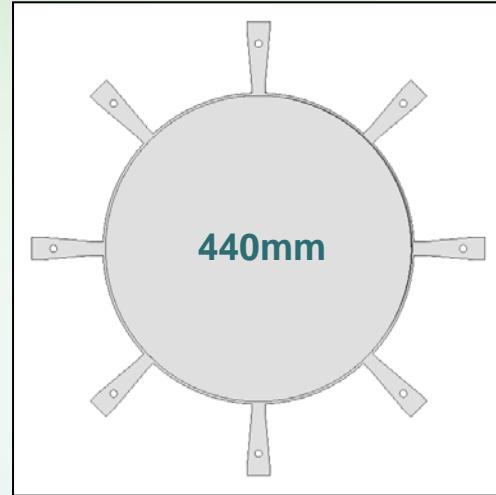


Planarity change as the Back-stiffener's thickness

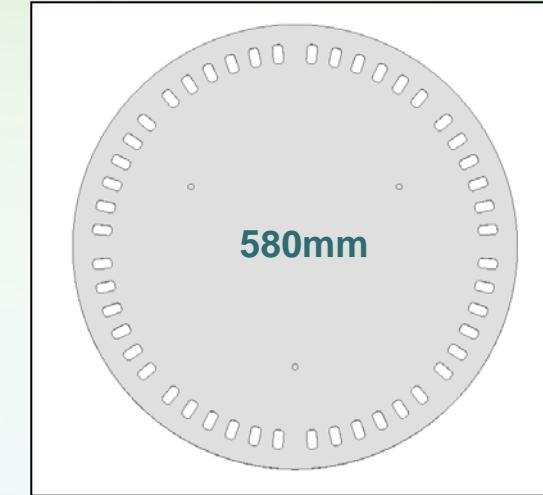


Type of Back-stiffener

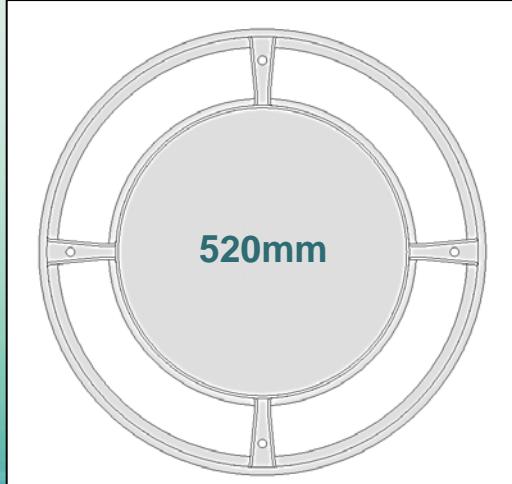
Volume type back-stiffener



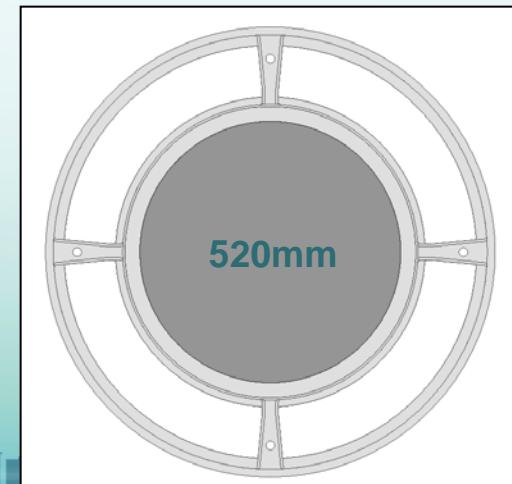
Large area type back-stiffener



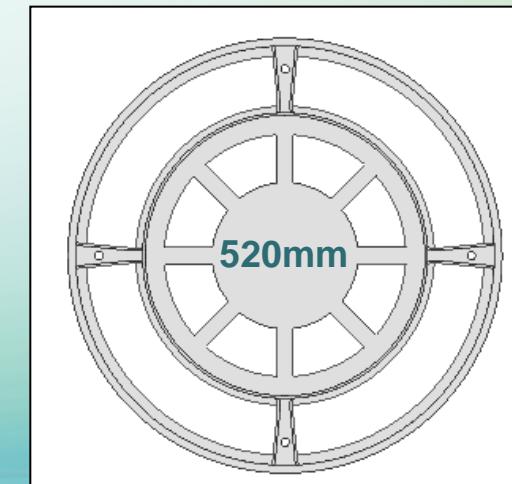
Volume type back-stiffener 1



Volume type back-stiffener 2



Relay board type back-stiffener



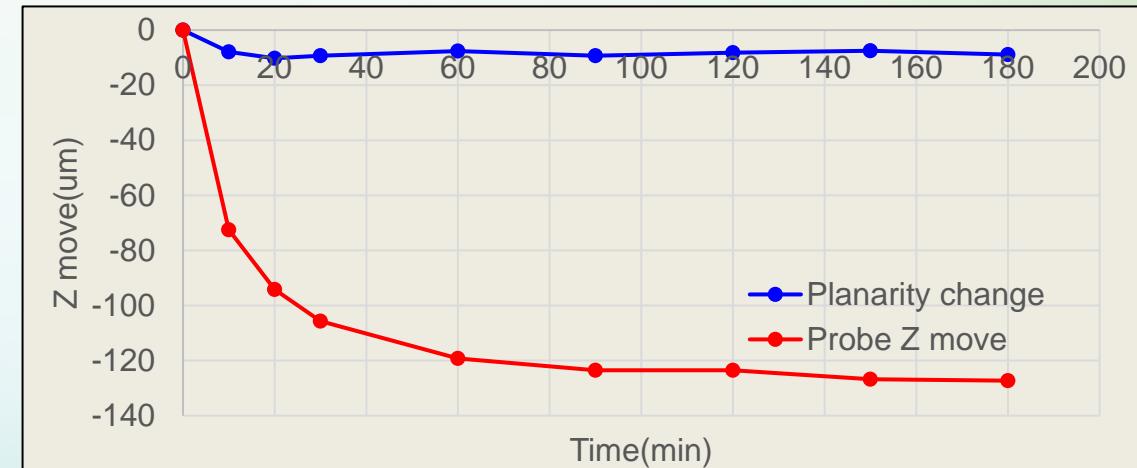
Experiment of thermal planarity

PROBER system



| Temperature | Value |
|-------------------------|-------|
| Test temperature(°C) | 100 |
| Ambient temperature(°C) | 25 |

Probe Z move and planarity change



| Time(min) | 0 | 10 | 20 | 30 | 60 | 90 | 120 | 150 | 180 |
|----------------------|-----|-------|-------|--------|--------|--------|--------|--------|--------|
| Z move (um) | 0.0 | -72.5 | -94.2 | -105.7 | -119.2 | -123.5 | -123.5 | -126.8 | -127.3 |
| Planarity change(um) | 0.0 | -7.9 | -10.2 | -9.3 | -7.6 | -9.3 | -8.2 | -7.5 | -8.9 |

Comparison with FEA and Experiment

| ITEM | Target | FEA | Experiment |
|------------------|---------|----------|------------|
| Planarity change | +/- 5um | -5 ~ 3um | -4 ~ 2um |

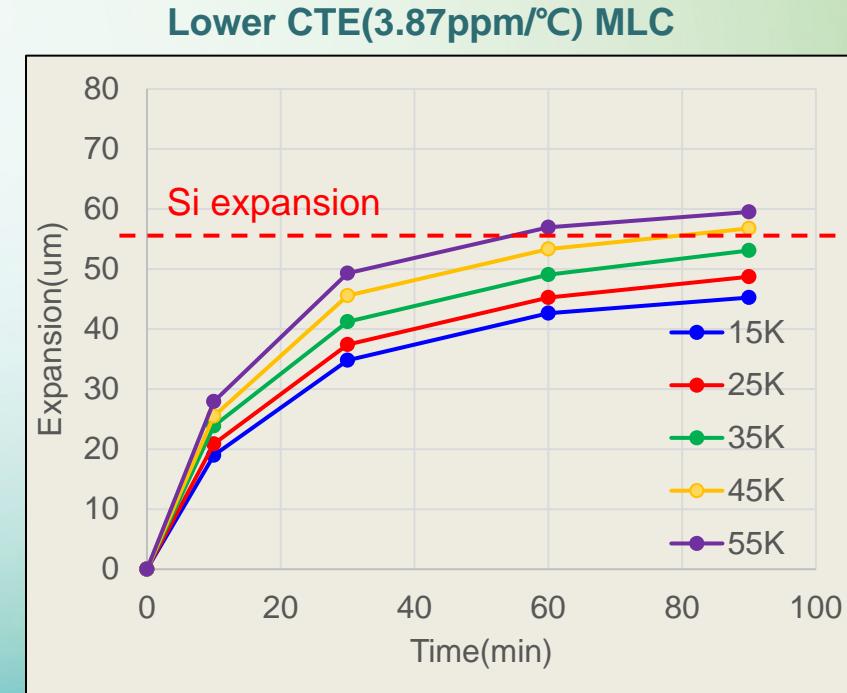
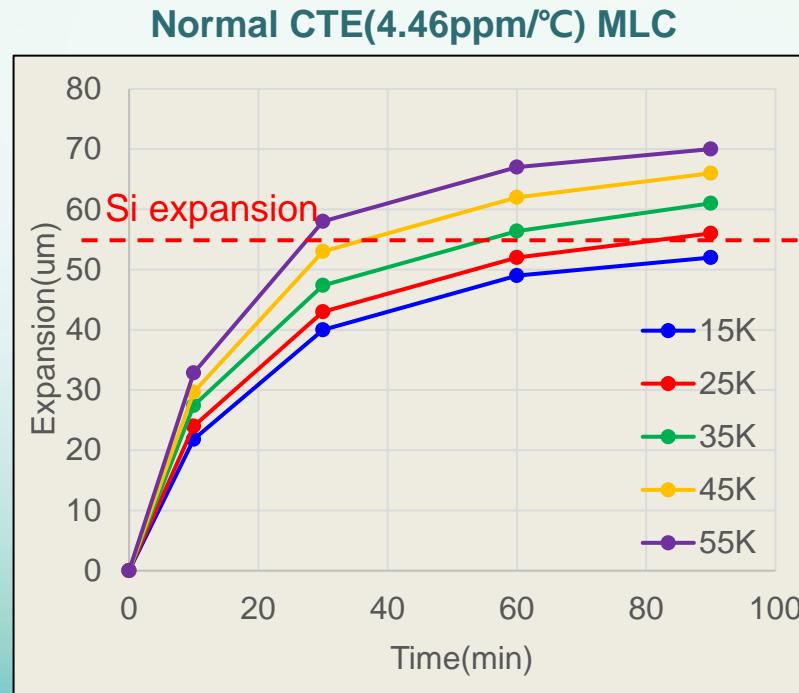
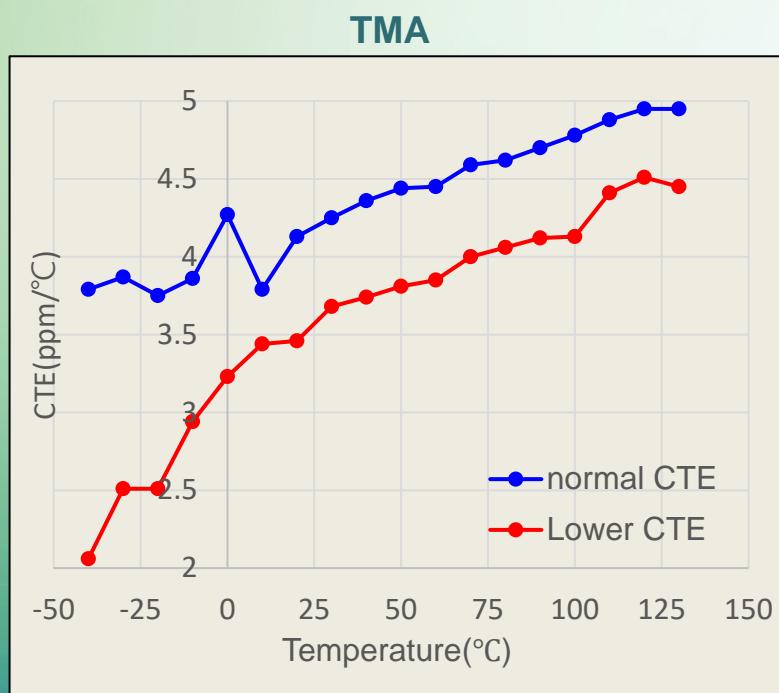
| Tester | Back-stiffener size | Material | Temperature(°C) | Planarity change FEA | Planarity change Experiment | Error (FEA-Experiment) |
|--------|---------------------|----------|-----------------|-------------------------|--------------------------------|---------------------------|
| A | 440 | SUS420 | 100°C | -5um | -4um | -1um |
| B | 480 | SUS420 | 85°C | -5um | -4um | -1um |
| C | 520 | SUS310S | 110°C | -5um | -4um | -1um |
| | 580 | SUS304 | 110°C | -4um | -3um | -1um |
| | 520 | SUS310S | 150°C | 3um | 2um | 1um |

Mainly SUS420 and SUS310S are used and a planarity change of less than +/-5μm is achieved.

Optimization of thermal alignment

- Lower CTE MLC

- 1) Manufacturer of lower CTE MLC : SEMCNS
- 2) Lower CTE value : 3.87 ppm/ $^{\circ}\text{C}$ (normal CTE 4.46 ppm/ $^{\circ}\text{C}$, at 25~100 $^{\circ}\text{C}$)
- 3) Higher probe counts : Suitable for lower CTE MLC



Measurement of lower CTE MLC

- Thermal expansion measuring condition

- Test temperature : 100°C
- Test sample : 300mm MLC
- Test time : expansion measured after 2hours(full heating)
- Test equipment : Auto 3D scope
- Test data

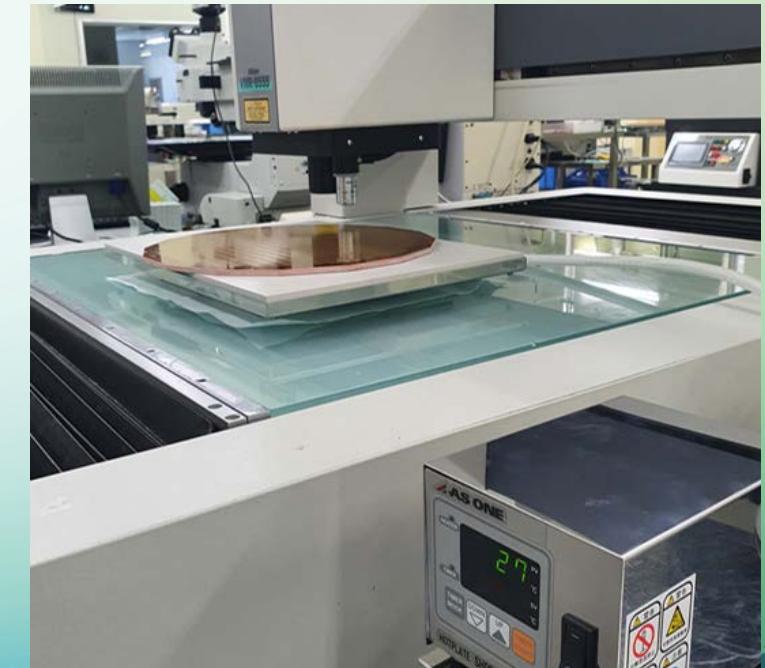
| Sample | 25°C | | 100°C | | Expansion (um) |
|--------------|-------------------------|------------------------|-------------------------|------------------------|-------------------|
| | Initial Temperature(°C) | Measuring Distance(um) | Initial Temperature(°C) | Measuring Distance(um) | |
| Normal CTE A | 27.0 | 291640.4 | 99.8 | 291734.0 | 96.3 |
| Normal CTE B | 26.3 | 291637.3 | 99.8 | 291728.5 | 93.7 |
| Lower CTE A | 26.3 | 305825.1 | 99 | 305913.6 | 86.7 |
| Lower CTE B | 27.2 | 305825.0 | 99 | 305913.2 | 86.4 |

Decrease 8.4um thermal expansion compared with normal CTE

SEMCNS specification

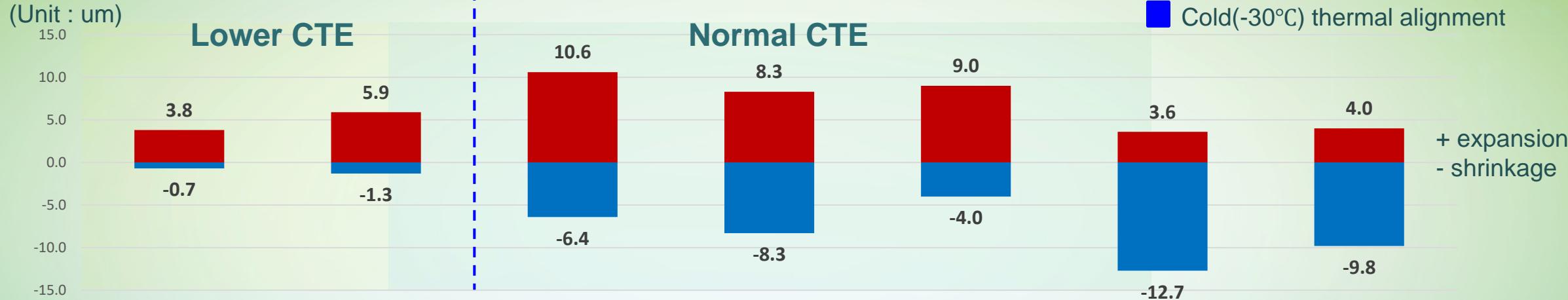
| TMA | Normal CTE | Lower CTE |
|-----------|-------------|-------------|
| 25~100°C | 4.46 ppm/°C | 3.87 ppm/°C |
| -40~120°C | 4.29 ppm/°C | 3.81 ppm/°C |

Measurement system



Thermal alignment applied probe card

300mm NAND FLASH(probe count about 43K)

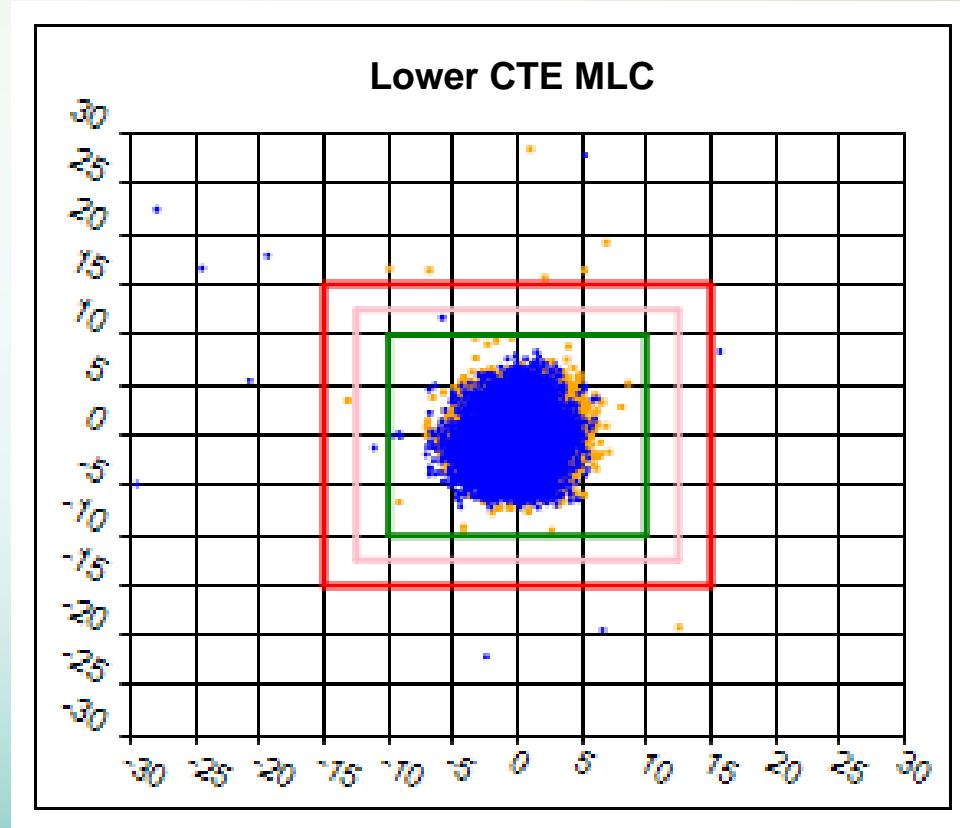
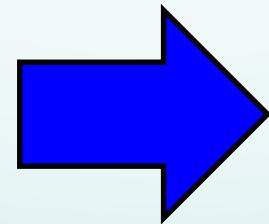
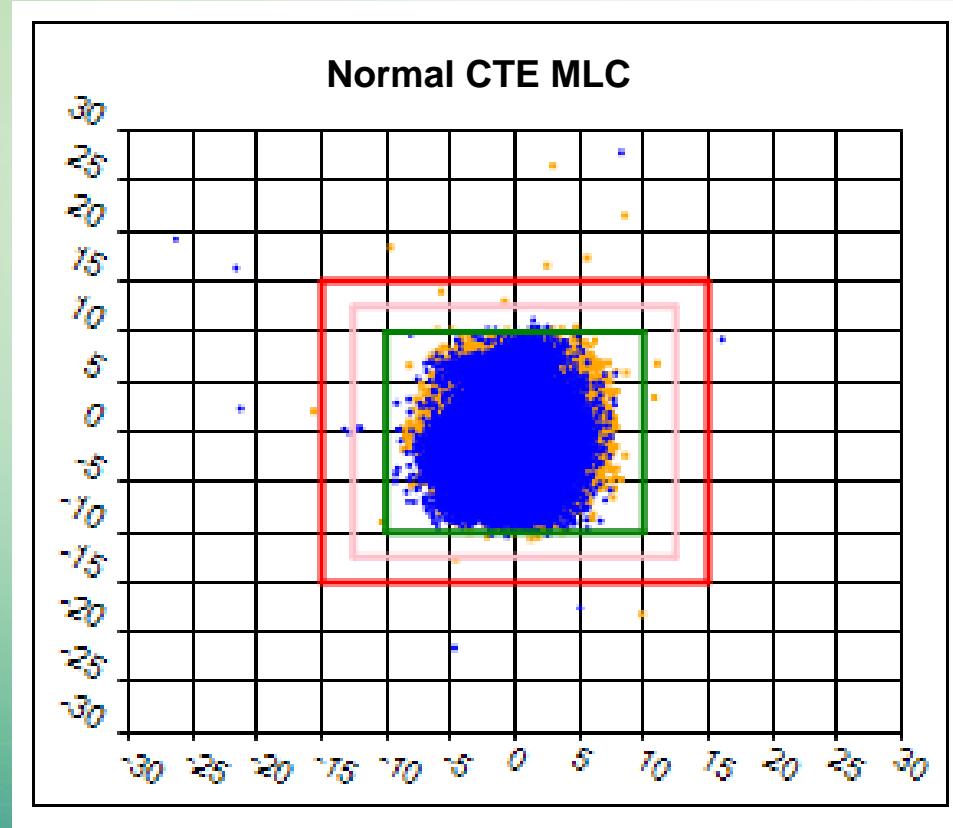


| Probe card | MLC | CTE | Hot expansion direction | Cold expansion direction | Symmetry |
|-------------|-----|--------|-------------------------|--------------------------|----------|
| Same device | A | Lower | 3.8 | -0.7 | 4.5 |
| | B | | 5.9 | -1.3 | 7.2 |
| | C | Normal | 10.6 | -6.4 | 17.0 |
| | D | | 8.3 | -8.3 | 16.6 |
| | E | | 9.0 | -4.0 | 13.0 |
| | F | | 3.6 | -12.7 | 16.3 |
| | G | | 4.0 | -9.8 | 13.8 |
| | Avg | Low | 4.9 | -1.0 | 5.9 |
| | | Normal | 7.1 | -8.2 | 15.3 |

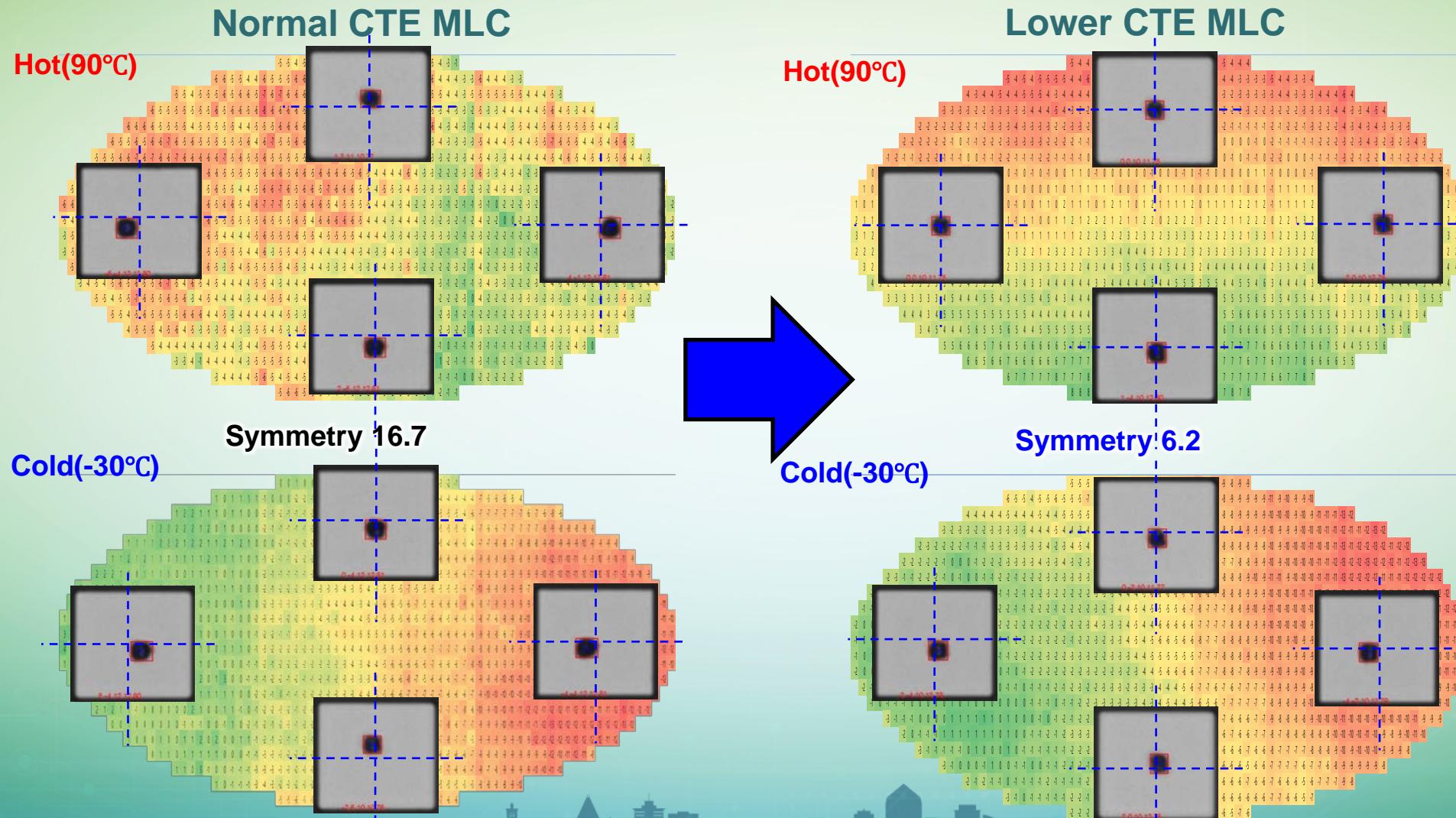
Improvement thermal alignment 9.4um compared with normal CTE

Thermal alignment diagram

300mm NAND FLASH(probe count about 43K) One shot thermal alignment diagram(90°C)



Probe mark inspection applied lower CTE MLC



Summary

- **Thermo-mechanical properties of probe card**
 - **Thermal planarity**
 - 1) Main factor of thermal planarity : Back-stiffener
 - Size of back-stiffener : Large impact in the thermal Z movement of the probe card
 - Larger size of back-stiffener : Suitable for material with higher CTE, stable for planarity change
 - 2) Planarity change(target : +/-5um)
 - FEA : - 5 ~ 3um
 - Experiment : - 4 ~ 2um
 - **Thermal alignment**
 - 1) Number of probes : Important factor in selecting CTE of MLC
 - Lower CTE(3.87ppm/ $^{\circ}$ C) MLC : Improvement of thermal alignment 9.4um compared with normal CTE (4.46ppm/ $^{\circ}$ C)MLC with 43K probe card
 - 2) Probe counts for stable alignment(300mm probe card)
 - Normal CTE(4.46ppm/ $^{\circ}$ C) MLC : From 20K to 30K probe counts
 - Lower CTE(3.87ppm/ $^{\circ}$ C) MLC : From 35K to 55K probe counts